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PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Hideo SHITE

U.S. Serial No.: 10/538,727

Group Art Unit: 1792

Filed: June 13, 2005

Examiner: Kirsten Jolley

For: COATING PROCESS APPARATUS AND COATING FILM FORMING METHOD

SECOND INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Pursuant to the duty of disclosure under 37 C.F.R. 1.56, Applicant encloses an Information Disclosure Citation Form (PTO-1449) and copy of the Japanese documents cited therein.

Applicant certifies under 37 C.F.R. 1.97(e)(1) that each item of information contained in this Information Disclosure Statement was first cited in communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

It is respectfully requested that the cited documents be considered by the Examiner, that it be made officially of record therein, and that the document be listed on the face of any patent which may issue from this application.

Respectfully submitted,
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By:


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